

# Ultrahigh Vacuum, Chemical Vapor Deposition

#### Introduction

Chemical vapor deposition (CVD) is a process often used in the semiconductor industry for epitaxial layer growth of high-purity silicon on top of a wafer substrate.

CVD is achieved using many different techniques and across a range of pressures; however, of particular commercial interest is the multilayer ultrahigh vacuum (UHV)/CVD technique.

UHV/CVD is performed at pressures below  $10^{-6}$  Pa ( $10^{-8}$  Torr), so gas transport is achieved by molecular flow and lacks any hydrodynamic effects such as boundary layers. In addition, there is also no gas-phase chemistry involved due to the low frequency of molecular collisions, so growth rate will be determined by the number density of species and surface molecular decomposition processes.

# Model Definition

Typically wafers are arranged close together (relative to their diameters) on a movable wafer boat within a quartz tube, surrounded by a furnace. Reactant gases are introduced at one end via a load lock together with a dilution gas such as hydrogen. A turbopump is present at the other end of the quartz tube.

The model geometry is shown in Figure 1. The wafer cassette is positioned within the quartz chamber by means of a delivery rail.

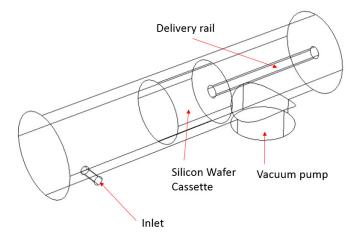


Figure 1: Model geometry. Key components of the system are labeled.

The reactant gas, silane (SiH<sub>4</sub>) along with a dilution gas, hydrogen (H<sub>2</sub>) enters through the inlet. The total gas mass flow rate is 1 SCCM (0.2 SCCM SiH<sub>4</sub>, 0.8 SCCM H<sub>2</sub>). The outgassing wall boundary condition is used for this inlet.

A vacuum pump is positioned at the other end of the chamber at the cylindrical port. Three different pumping curves are investigated for both the hydrogen and the silane. These pumping curves are loaded into COMSOL Multiphysics as interpolations functions and are switched between using a sweep parameter that will allow us to run the model for each curve.

All other surfaces in the model are walls.

#### Results and Discussion

The molecular flux fraction of SiH4 at the wafer cassette, using pumping curves 2, is shown in Figure 2. The interesting result is that the molecular flux fraction of silane at the wafer cassette is significantly different from what is introduced at the inlet. As this directly controls the growth on the wafers, the choice of pump seems to be important. In addition, this molecular flux fraction cannot easily be measures at the wafer so its important to use models like this to investigate the process fully.

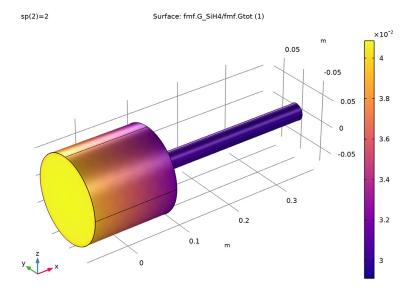


Figure 2: Molecular flux fraction of SiH<sub>4</sub> at the water cassette.

# Reference

1. B. S. Meyerson, Appl. Phys. Lett. 48, pp. 797–799, 1986.

**Application Library path:** Molecular\_Flow\_Module/Industrial\_Applications/ uhv\_cvd

# Modeling Instructions

From the File menu, choose New.

In the New window, click Model Wizard.

#### MODEL WIZARD

I In the Model Wizard window, click 1 3D.

- 2 In the Select Physics tree, select Fluid Flow>Rarefied Flow>Free Molecular Flow (fmf).
- 3 Click Add.
- 4 Click 🗪 Study.
- 5 In the Select Study tree, select General Studies>Stationary.
- 6 Click M Done.

#### **GLOBAL DEFINITIONS**

#### Parameters 1

- I In the Model Builder window, under Global Definitions click Parameters I.
- 2 In the Settings window for Parameters, locate the Parameters section.
- 3 Click **Load from File**.
- **4** Browse to the model's Application Libraries folder and double-click the file uhv\_cvd\_parameters.txt.

#### GEOMETRY I

The geometry consists of a cylindrical chamber with an inlet and vacuum pump at either end. A cassette of Silicon wafers is approximated by a cylinder of narrower diameter on the end of a delivery rail.

## Cylinder I (cyl1)

- I In the Geometry toolbar, click Cylinder.
- 2 In the Settings window for Cylinder, locate the Size and Shape section.
- 3 In the Radius text field, type R0.
- **4** In the **Height** text field, type L0.
- 5 Locate the **Position** section. In the x text field, type -Lo/2.
- 6 Locate the Axis section. From the Axis type list, choose x-axis.
- 7 Locate the **Position** section. In the x text field, type -L0/2.

#### Cylinder 2 (cyl2)

- I In the Geometry toolbar, click Cylinder.
- 2 In the Settings window for Cylinder, locate the Size and Shape section.
- 3 In the Radius text field, type Dp/2.
- 4 In the Height text field, type Dp/4+R0.
- **5** Locate the **Position** section. In the **x** text field, type 0.3\*L0.
- 6 In the z text field, type (RO+Dp/4).

Union I (uni I)

- I In the Geometry toolbar, click Booleans and Partitions and choose Union.
- 2 Click in the **Graphics** window and then press Ctrl+A to select both objects.
- 3 In the Settings window for Union, locate the Union section.
- 4 Clear the Keep interior boundaries check box.

Cylinder 3 (cyl3)

- I In the Geometry toolbar, click Cylinder.
- 2 In the Settings window for Cylinder, locate the Size and Shape section.
- 3 In the Radius text field, type Dw/2.
- 4 In the Height text field, type Lw.
- 5 Locate the **Position** section. In the **x** text field, type -Lw/2.
- **6** Locate the **Axis** section. From the **Axis type** list, choose **x-axis**.

Cylinder 4 (cyl4)

- I In the Geometry toolbar, click Cylinder.
- 2 In the Settings window for Cylinder, locate the Size and Shape section.
- 3 In the Radius text field, type Dw/10.
- 4 In the **Height** text field, type L0/2.
- **5** Locate the **Axis** section. From the **Axis type** list, choose **x-axis**.

Union 2 (uni2)

- I In the Geometry toolbar, click Booleans and Partitions and choose Union.
- 2 Click the Wireframe Rendering button in the Graphics toolbar.
- 3 Select the objects cyl3 and cyl4 only.
- 4 In the Settings window for Union, locate the Union section.
- **5** Clear the **Keep interior boundaries** check box.

Difference I (dif1)

- I In the Geometry toolbar, click Booleans and Partitions and choose Difference.
- 2 Select the object unil only.
- 3 In the Settings window for Difference, locate the Difference section.
- 4 Find the **Objects to subtract** subsection. Click to select the **Activate Selection** toggle button.
- **5** Select the object **uni2** only.

### Cylinder 5 (cyl5)

- I In the Geometry toolbar, click ( Cylinder.
- 2 In the Settings window for Cylinder, locate the Size and Shape section.
- 3 In the Radius text field, type Rin.
- 4 In the Height text field, type 1.5\*(R0).
- 5 Locate the Position section. In the x text field, type -0.9\*L0/2.
- 6 In the y text field, type -1.5\*R0.
- 7 Locate the Axis section. From the Axis type list, choose y-axis.

#### Difference 2 (dif2)

- I In the Geometry toolbar, click Booleans and Partitions and choose Difference.
- **2** Select the object **cyl5** only.
- 3 In the Settings window for Difference, locate the Difference section.
- 4 Find the **Objects to subtract** subsection. Click to select the Activate Selection toggle button.
- **5** Select the object **difl** only.
- 6 Select the Keep objects to subtract check box.
- 7 Click **Build All Objects**.

#### DEFINITIONS

Set up some selections to assist during postprocessing.

#### Cassette

- I In the **Definitions** toolbar, click **\( \bigcap\_{\bigcap} \) Explicit**.
- 2 In the Settings window for Explicit, locate the Input Entities section.
- 3 From the Geometric entity level list, choose Boundary.
- 4 Select Boundaries 13–18 only.
- 5 In the Label text field, type Cassette.

#### Cassette and rail

- I In the **Definitions** toolbar, click 🔓 **Explicit**.
- 2 In the Settings window for Explicit, locate the Input Entities section.
- **3** From the **Geometric entity level** list, choose **Boundary**.
- 4 Select Boundaries 13–22 only.
- 5 In the Label text field, type Cassette and rail.

Interpolation I (int I)

- I In the **Definitions** toolbar, click . Interpolation.
- 2 In the Settings window for Interpolation, locate the Definition section.
- 3 Click **Load from File**.
- **4** Browse to the model's Application Libraries folder and double-click the file uhv\_cvd\_turbopump01\_H2.txt.
- 5 In the Function name text field, type pump1\_H2.
- 6 Locate the Units section. In the Argument table, enter the following settings:

Argument	Unit
t	hPa

7 In the Function table, enter the following settings:

Function	Unit
pump I_H2	1/s

Interpolation 2 (int2)

- I In the **Definitions** toolbar, click ... **Interpolation**.
- 2 In the Settings window for Interpolation, locate the Definition section.
- 3 Click **Load from File**.
- **4** Browse to the model's Application Libraries folder and double-click the file uhv\_cvd\_turbopump02\_H2.txt.
- 5 In the Function name text field, type pump2\_H2.
- 6 Locate the Units section. In the Argument table, enter the following settings:

Argument	Unit
t	hPa

7 In the **Function** table, enter the following settings:

Function	Unit
pump2_H2	1/s

Interpolation 3 (int3)

- I In the **Definitions** toolbar, click **\(\cdot\) Interpolation**.
- 2 In the Settings window for Interpolation, locate the Definition section.
- 3 Click **Load from File**.

- **4** Browse to the model's Application Libraries folder and double-click the file uhv\_cvd\_turbopump03\_H2.txt.
- 5 In the Function name text field, type pump3\_H2.
- 6 Locate the **Units** section. In the **Argument** table, enter the following settings:

Argument	Unit
t	hPa

7 In the Function table, enter the following settings:

Function	Unit
pump3_H2	1/s

Interpolation 4 (int4)

- I In the **Definitions** toolbar, click . Interpolation.
- 2 In the Settings window for Interpolation, locate the Definition section.
- 3 Click Load from File.
- **4** Browse to the model's Application Libraries folder and double-click the file uhv cvd turbopump01 SiH4.txt.
- 5 In the Function name text field, type pump1\_SiH4.
- 6 Locate the **Units** section. In the **Argument** table, enter the following settings:

Argument	Unit
t	hPa

**7** In the **Function** table, enter the following settings:

Function	Unit
pump I_SiH4	1/s

Interpolation 5 (int5)

- I In the **Definitions** toolbar, click **\(\cdot\) Interpolation**.
- 2 In the Settings window for Interpolation, locate the Definition section.
- 3 Click Load from File.
- **4** Browse to the model's Application Libraries folder and double-click the file uhv\_cvd\_turbopump02\_SiH4.txt.
- 5 In the Function name text field, type pump2\_SiH4.

**6** Locate the **Units** section. In the **Argument** table, enter the following settings:

Argument	Unit
t	hPa

7 In the Function table, enter the following settings:

Function	Unit
pump2_SiH4	1/s

Interpolation 6 (int6)

- I In the **Definitions** toolbar, click . Interpolation.
- $\boldsymbol{2}$  In the Settings window for Interpolation, locate the Definition section.
- 3 Click **Load from File**.
- 4 Browse to the model's Application Libraries folder and double-click the file uhv\_cvd\_turbopump03\_SiH4.txt.
- 5 In the Function name text field, type pump3\_SiH4.
- **6** Locate the **Units** section. In the **Argument** table, enter the following settings:

Argument	Unit
t	hPa

7 In the **Function** table, enter the following settings:

Function	Unit
pump3_SiH4	1/s

Set up two species, Silane (SiH4) and Hydrogen (H2) as a dilution gas.

#### FREE MOLECULAR FLOW (FMF)

- I In the Model Builder window, under Component I (compl) click Free Molecular Flow (fmf).
- 2 In the Settings window for Free Molecular Flow, click to expand the Dependent Variables section.
- 3 In the Number of species text field, type 2.
- **4** In the **Incident molecular fluxes** table, enter the following settings:

H2 SiH4 5 Locate the Compute section. Clear the Number density check box.

Specify the molecular weights for both species.

#### Molecular Flow 1

- I In the Model Builder window, under Component I (compl)>Free Molecular Flow (fmf) click Molecular Flow I.
- 2 In the Settings window for Molecular Flow, locate the Molecular Weight of Species section.
- **3** In the  $M_{\rm n~H2}$  text field, type 2[g/mol].
- **4** In the  $M_{\text{n.SiH4}}$  text field, type 32.12[g/mol].

Set the temperature of the surrounding furnace.

#### Surface Temperature 1

- I In the Model Builder window, click Surface Temperature I.
- 2 In the Settings window for Surface Temperature, locate the Surface Temperature section.
- **3** In the *T* text field, type Tf.

Add an outgassing wall to the inlet with the mass flows of each species.

#### Wall 2

- I In the Physics toolbar, click **Boundaries** and choose Wall.
- **2** Select Boundary 8 only.
- 3 In the Settings window for Wall, locate the Wall Type section.
- 4 From the Wall type list, choose Outgassing wall.
- 5 Locate the Flux section. From the Outgoing flux list, choose Number of SCCM units.
- **6** In the  $Q_{\text{sccm},H2}$  text field, type sccmH2.
- **7** In the  $Q_{
  m sccm.SiH4}$  text field, type sccmSiH4.

Add a vacuum pump and specify the pump speed for each species.

#### Vacuum Pump I

- I In the Physics toolbar, click Boundaries and choose Vacuum Pump.
- 2 Select Boundary 25 only.
- 3 In the Settings window for Vacuum Pump, locate the Vacuum Pump section.
- 4 From the Specify pump flux list, choose Pump speed.
- 5 In the  $S_{\rm H2}$  text field, type pump1\_H2(fmf.ptot)\*(sp==1)+pump2\_H2(fmf.ptot)\* (sp==2)+pump3 H2(fmf.ptot)\*(sp==3).

**6** In the  $S_{\mathrm{SiH4}}$  text field, type pump1\_SiH4(fmf.ptot)\*(sp==1)+ pump2 SiH4(fmf.ptot)\*(sp==2)+pump3 SiH4(fmf.ptot)\*(sp==3).

Add a surface mesh.

#### MESH I

Free Triangular 1

- I In the Mesh toolbar, click A Boundary and choose Free Triangular.
- 2 In the Settings window for Free Triangular, locate the Boundary Selection section.
- 3 From the Selection list, choose Cassette and rail.

Size 1

- I Right-click Free Triangular I and choose Size.
- 2 In the Settings window for Size, locate the Element Size section.
- 3 From the Predefined list, choose Extra fine.

Free Triangular 2

- I In the Mesh toolbar, click A Boundary and choose Free Triangular.
- 2 In the Settings window for Free Triangular, locate the Boundary Selection section.
- 3 From the Geometric entity level list, choose Remaining.

Size

- I In the Model Builder window, click Size.
- 2 In the Settings window for Size, locate the Element Size section.
- 3 From the Predefined list, choose Finer.

Add two average nonlocal couplings to allow the evaluation of properties on and around the wafer cassette and vacuum pump.

#### DEFINITIONS

Average I (aveop1)

- I In the Definitions toolbar, click // Nonlocal Couplings and choose Average.
- 2 In the Settings window for Average, locate the Source Selection section.
- 3 From the Geometric entity level list, choose Boundary.
- 4 From the Selection list, choose Cassette.

Average 2 (aveob2)

I In the Definitions toolbar, click Monlocal Couplings and choose Average.

- 2 In the Settings window for Average, locate the Source Selection section.
- 3 From the Geometric entity level list, choose Boundary.
- 4 Select Boundary 25 only.

Set the study up to cover a range of inlet mass flows for pump 1, 2, and 3.

#### STUDY I

Step 1: Stationary

- I In the Model Builder window, under Study I click Step I: Stationary.
- 2 In the Settings window for Stationary, click to expand the Study Extensions section.
- 3 Select the Auxiliary sweep check box.
- 4 Click + Add.
- 5 In the table, enter the following settings:

Parameter name	Parameter value list	Parameter unit
sp (Sweep parameter)	1 2 3	

**6** In the **Home** toolbar, click **Compute**.

#### RESULTS

Study I/Solution I (2) (soll)

- I In the Model Builder window, expand the Results>Datasets node.
- 2 Right-click Results>Datasets>Study I/Solution I (soll) and choose Duplicate.

#### Selection

- I In the Results toolbar, click \( \frac{1}{2} \) Attributes and choose Selection.
- 2 In the Settings window for Selection, locate the Geometric Entity Selection section.
- 3 From the Geometric entity level list, choose Boundary.
- 4 From the Selection list, choose Cassette and rail.

Add a Global Evaluation node to evaluate the molecular flux of SiH4 and molecular flux fraction of SiH4 at the position of the cassette, as well as the average pressure at the vacuum pump.

#### Global Evaluation 1

- I In the Results toolbar, click (8.5) Global Evaluation.
- 2 In the Settings window for Global Evaluation, locate the Expressions section.

**3** In the table, enter the following settings:

Expression	Unit	Description
aveop1(fmf.G_SiH4)	1/(m^2*s)	SiH4 flux
<pre>aveop1(fmf.G_SiH4/fmf.Gtot)</pre>	1	Flux fraction
aveop2(fmf.ptot)	Pa	Pump pressure

4 Click **= Evaluate**.

#### Molecular Flux Fraction SiH4

- I In the Results toolbar, click **3D Plot Group**.
- 2 In the Settings window for 3D Plot Group, type Molecular Flux Fraction SiH4 in the Label text field.
- 3 Locate the Data section. From the Dataset list, choose Study I/Solution I (2) (soll).
- 4 From the Parameter value (sp) list, choose 2.

#### Surface I

- I Right-click Molecular Flux Fraction SiH4 and choose Surface.
- 2 In the Settings window for Surface, locate the Expression section.
- 3 In the Expression text field, type fmf.G\_SiH4/fmf.Gtot.
- 4 Locate the Coloring and Style section. Click Change Color Table.
- 5 In the Color Table dialog box, select Thermal>Plasma in the tree.
- 6 Click OK.
- 7 In the Molecular Flux Fraction SiH4 toolbar, click Plot.